

Practitioner's Docket No.: 782_200

PATENT

2834
et al
5-13-2

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of: Tomohiko SHIBATA, Yukinori NAKAMURA and
Mitsuhiko TANAKA

Ser. No.: 09/997,997

Art Unit: 2834

Filed: November 30, 2001

Examiner: Not Assigned

Confirmation No.: 3908

For: A SUBSTRATE USABLE FOR AN ACOUSTIC SURFACE WAVE DEVICE, A METHOD FOR FABRICATING THE SAME SUBSTRATE AND AN ACOUSTIC SURFACE WAVE DEVICE HAVING THE SAME SUBSTRATE

Assistant Commissioner for Patents
Washington, DC 20231

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail addressed to Assistant Commissioner for Patents, Washington D.C. 20231 on February 28, 2002.

Elizabeth A. VanAntwerp
Elizabeth A. VanAntwerp

INFORMATION DISCLOSURE STATEMENT

Sir:

Pursuant to 37 C.F.R. §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference listed on the attached Form PTO-1449. A copy of the reference listed on Form PTO-1449 is attached.

Reference AA is discussed at page 1 of the present specification.

The above information is presented so that the Patent and Trademark Office may, in the first instance, determine any materiality thereof to the claimed invention. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

The Commissioner is hereby authorized to charge any additional fees associated with this communication or credit any overpayment to Deposit Account No. 50-1446.

Respectfully submitted,

Kevin C. Brown

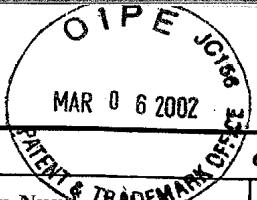
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Form PTO-1449

US DEPARTMENT OF COMMERCE
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

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Attorney Docket No.

Complete if Known

<p style="text-align: center;"><i>(use as many sheets as necessary)</i></p>			
<p>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</p>			
<p>Sheet <u>1</u> of <u>1</u></p>			
<i>Complete if Known</i>			
Application Number		09/997,997	
Filing Date		November 30, 2001	
First Named Inventor		Tomohiko SHIBATA	
Art Unit		2834	
Examiner Name		Not Assigned	
Confirmation No.		3908	
Attorney Docket No.		782_200	

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages etc.)

AA S. Kaneko, et al, "Epitaxial Growth of AlN Film by Low-pressure MOCVD in Gas-Beam-Flow Reactor," Journal of Crystal Growth, 115 (1991), pp. 643-647.

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.